U.S. Department of Commerce, Patent and Trademark Office							ney Docker	Application No.:			
PRODUMETION DISCLOSURE STATEMENT BY APPLICANT						NEC0252US Applicants:			Confirmation No.:		
						Applicants:			Commission No.:		
DEL 0.5. 2003						Filing Date:			Group Art Unit:		
									3		
U.S. Patent Documents Group Art Unit: 2											
*Examiner		Document	U.S. Fa		Т	Τ	Filing	Date			
Initial		Number	Date		Name		Class	Subclass	***		
	AA	6,358,835 B1	Mar. 19, 2002		Ryuichi Kanamura		438	618	Feb. 9, 2000		
	AB	6,507,474 B1	Jan. 14, 2003		Bhanwar Singh et al.		361	230	Jun. 19, 2000		
	AC	6,703,301 B2	Mar. 9, 2004		Chen Chung Tai et al.		438	620	Apr. 26, 2002		
	AD	6,872,699 B1	Mar. 29, 2005		Scott R. Summerfelt et al.		438	712	Dec. 19	, 2003	
	AE							<u> </u>			
	AF							_			
	AG						ļ		<u> </u>		
	AH										
·	AI								``		
	AJ						:_		\ \ \ \ \ \ \ \ \ \ \ \ \ \ \ \ \ \ \ \		
Patent Application Publication											
		Publication Number		Pub. Date	Name		Class	Subclass	Filing Date If Appropriate		
	AK	US 2004/0152395 A1		Aug. 5, 2004	Chung-Lung Yiu et al.		438	685	Jan. 30, 2003		
	AL										
	AM										
	AN										
Foreign Patent Documents											
									Translation		
		Document		Date	Country		Class	Subclass	Yes	No	
	AO		floor								
	AP		\perp								
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)											
	AQ										
	AR										
Examiner:							Date Considered:				
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.											